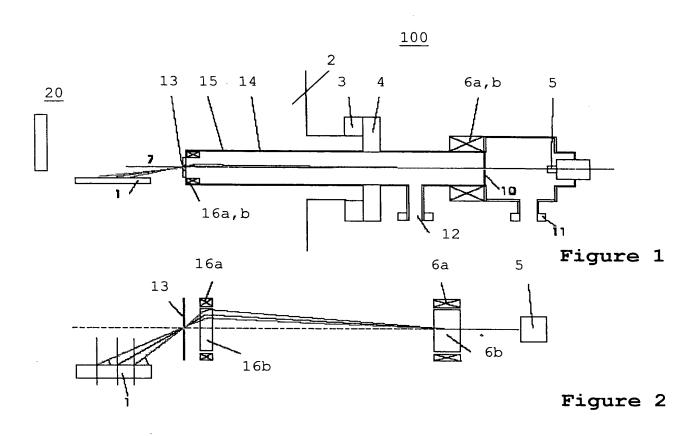
Applicant(s): Philippe Staib
Filed: September 17, 2003 Customer No. 03000
For: ELECTRON DIFFRACTION SYSTEM FOR
USE IN PRODUCTION ENVIRONMENT, etc.
Docket No.: B1180/20019 Sheet 1 of 3



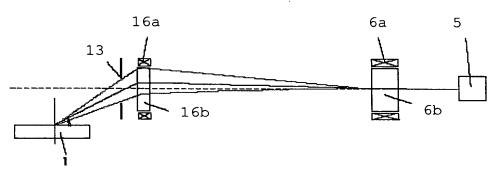


Figure 3

Applicant(s): Philippe Staib
Filed: September 17, 2003 Customer No. 03000
For: ELECTRON DIFFRACTION SYSTEM FOR
USE IN PRODUCTION ENVIRONMENT, etc. Docket No.: B1180/20019 Sheet 2 of 3

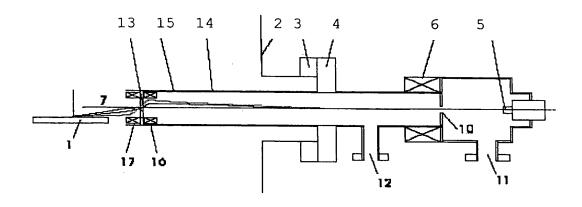


Figure 4

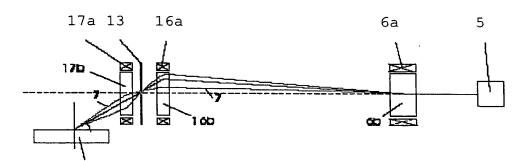
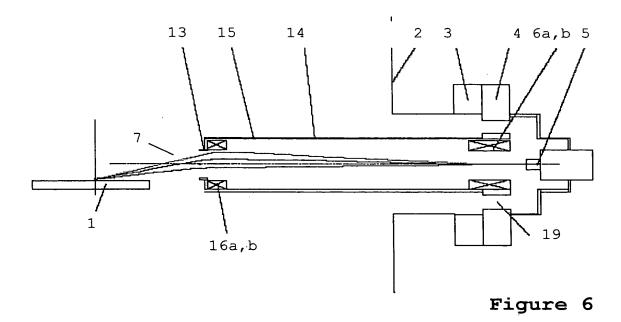
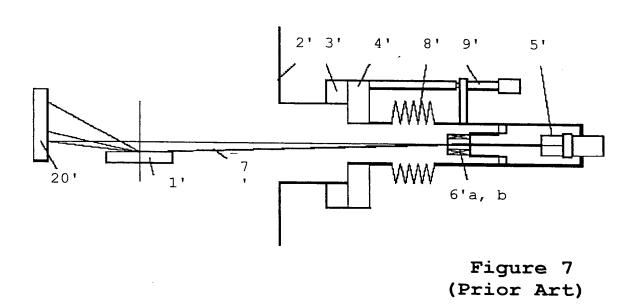


Figure 5



Applicant(s): Philippe Staib
Filed: September 17, 2003 Customer No. 03000
For: ELECTRON DIFFRACTION SYSTEM FOR
USE IN PRODUCTION ENVIRONMENT, etc.
Docket No.: B1180/20019 Sheet 3 of 3



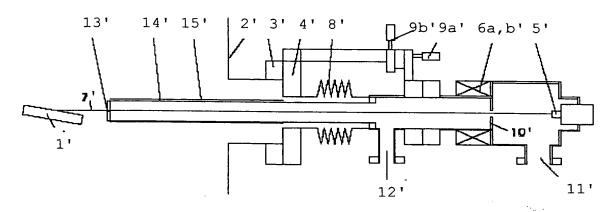


Figure 8 (Prior Art)